

Zulieferer

Facilities

exyte M MERCURY DAS

Equipment (Machinery)

ASML Lam TEL

APC - Advanced Process Control

kontron PEERGROUP onto

Chemicals

Air Liquide Linde CABOT

Parts & Components

VAT INFICON FESTO

Produktionsprozess

Inspection & Metrology

APPLIED MATERIALS make possible Nikon KLA

Wafer Manu- facturing

Shin-Etsu
SUMITOMO
siltronic

Mask Manu- facturing

TOPPAN
TOPPAN PHOTOMASK
DNP

Frontend Manu- facturing

SEMTEC Infineon
GlobalFoundries

Backend Manu- facturing

SES mkor
JCET

(Chip) Design

SYNOPSYS
arm
cadence

